

Motivation

- Repetitive patterns are ubiquitous in images
- Unless considered, they usually decrease vision algorithm performance

**Coplanar Repeats: Problem Formulation**

- Very *general definition* of a repeat; a single condition required:
mapped by rigid intra-planar transforms
- No regularity of repeats required, e.g. in a lattice
- No special image structure needed other than repetition, e.g.:
no parallel scene lines, axial symmetries or homologies needed
- We cover cases where:
repeats cover only a small part of the image
there are only a few repeats imaged

Contributions

- Automated method for coplanar repeat detection, rectification up to a similarity and pixel-level segmentation
- Linear geometric constraints and the necessary configurations of repeats for successive levels of rectification
- Generative model of repeated patterns inferred:
motif, intra-plane mappings, rectification and lens distortion
- Reduce SIFT variance by geometric refinement of features

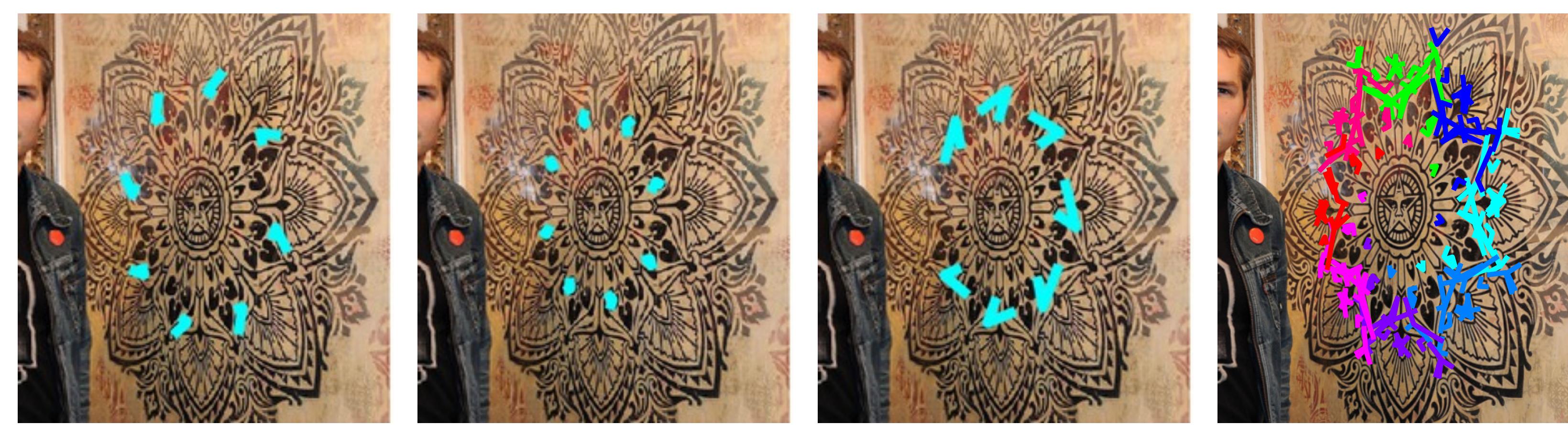
Repeats, Motifs, Instances and Patterns

Repeat: a photometrically consistent cluster of local affine frames satisfying a scale constraint (cf. Affine Rectification)

Motif: a spatially coherent collection of features

Instance: motif placed by one intra-planar mapping

Pattern: all instances of a motif in a single plane



Repeats

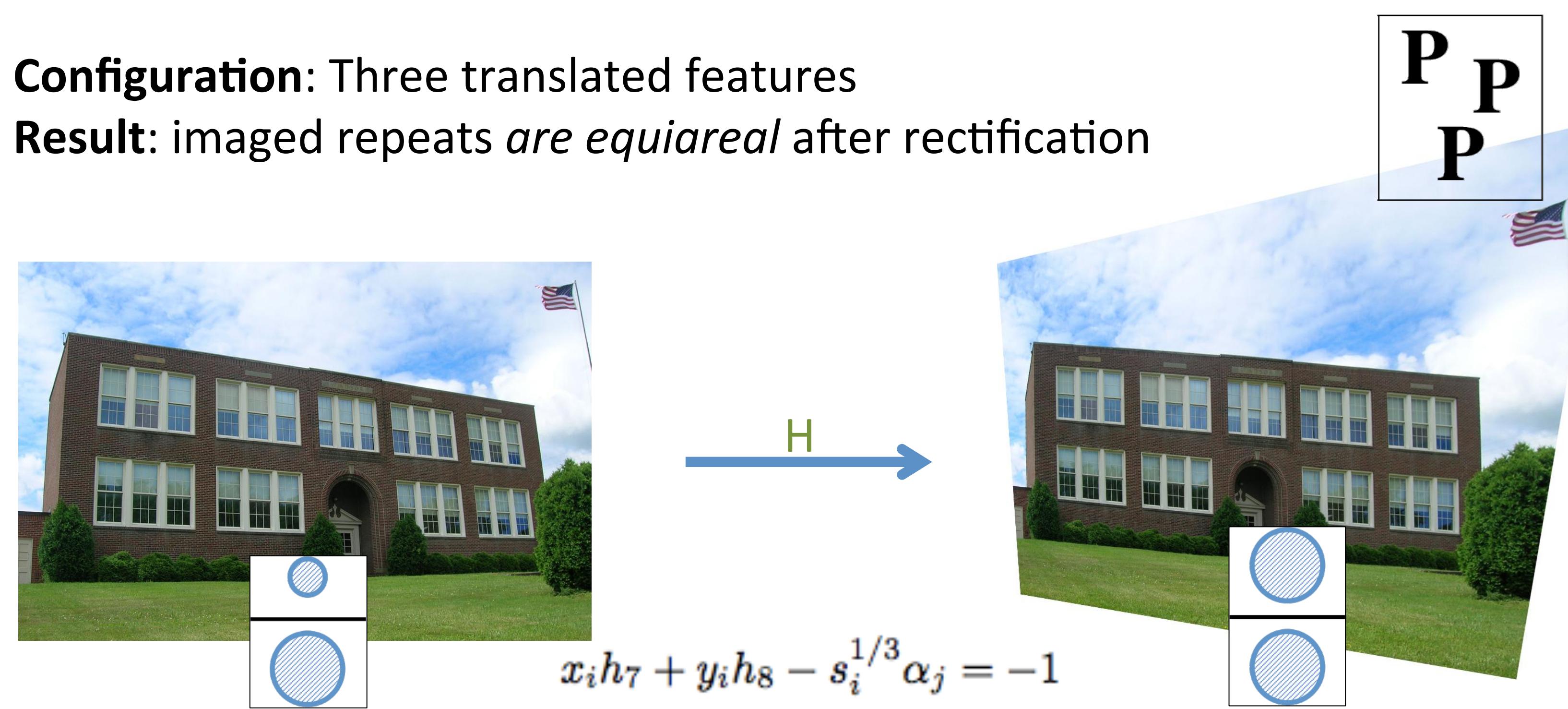
Pattern with color-coded Instances

Affine Rectification

Constraint: equiareal scene repeats means rectified repeats are equiareal.

Configuration: Three translated features

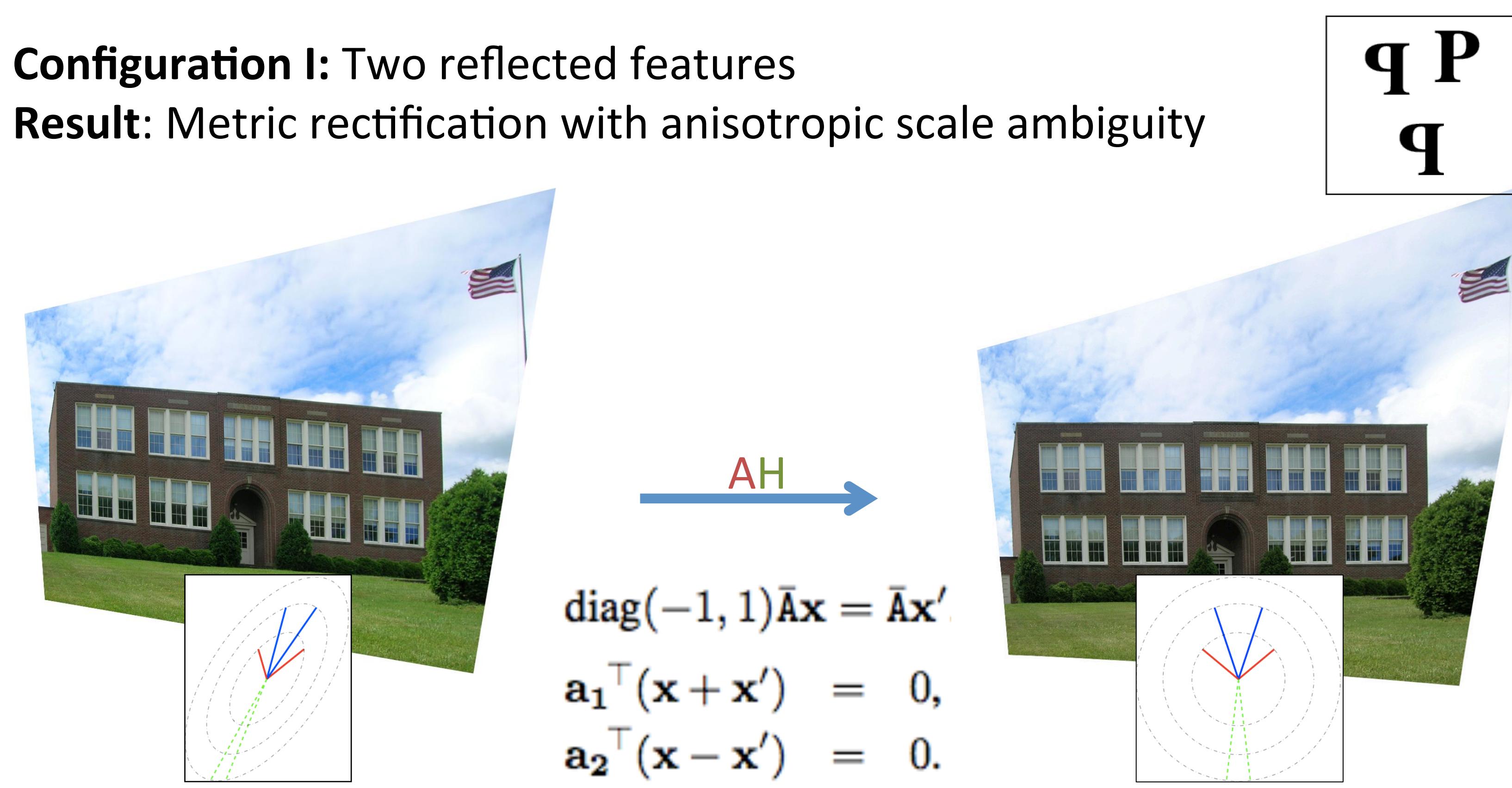
Result: imaged repeats are *equiareal* after rectification

**Metric Rectification**

Constraint: congruent scene extents means rectified repeats have congruent extents

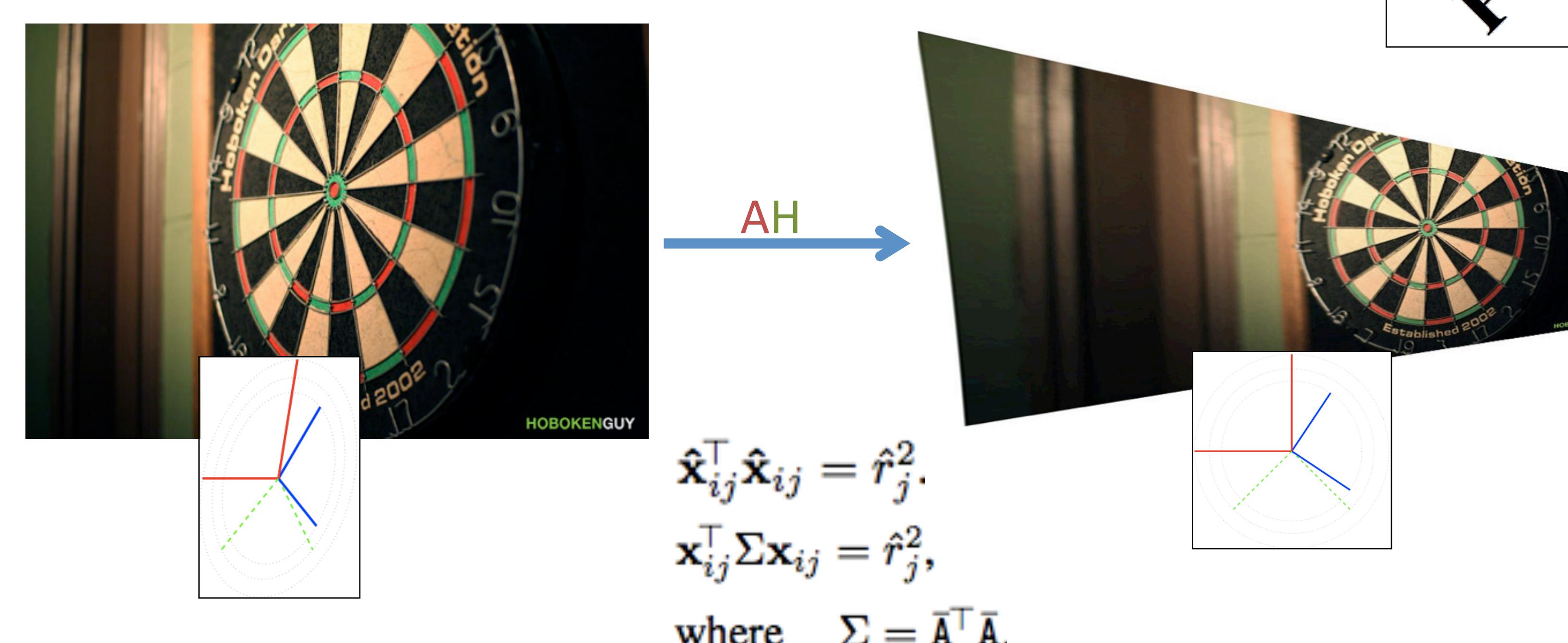
Configuration I: Two reflected features

Result: Metric rectification with anisotropic scale ambiguity

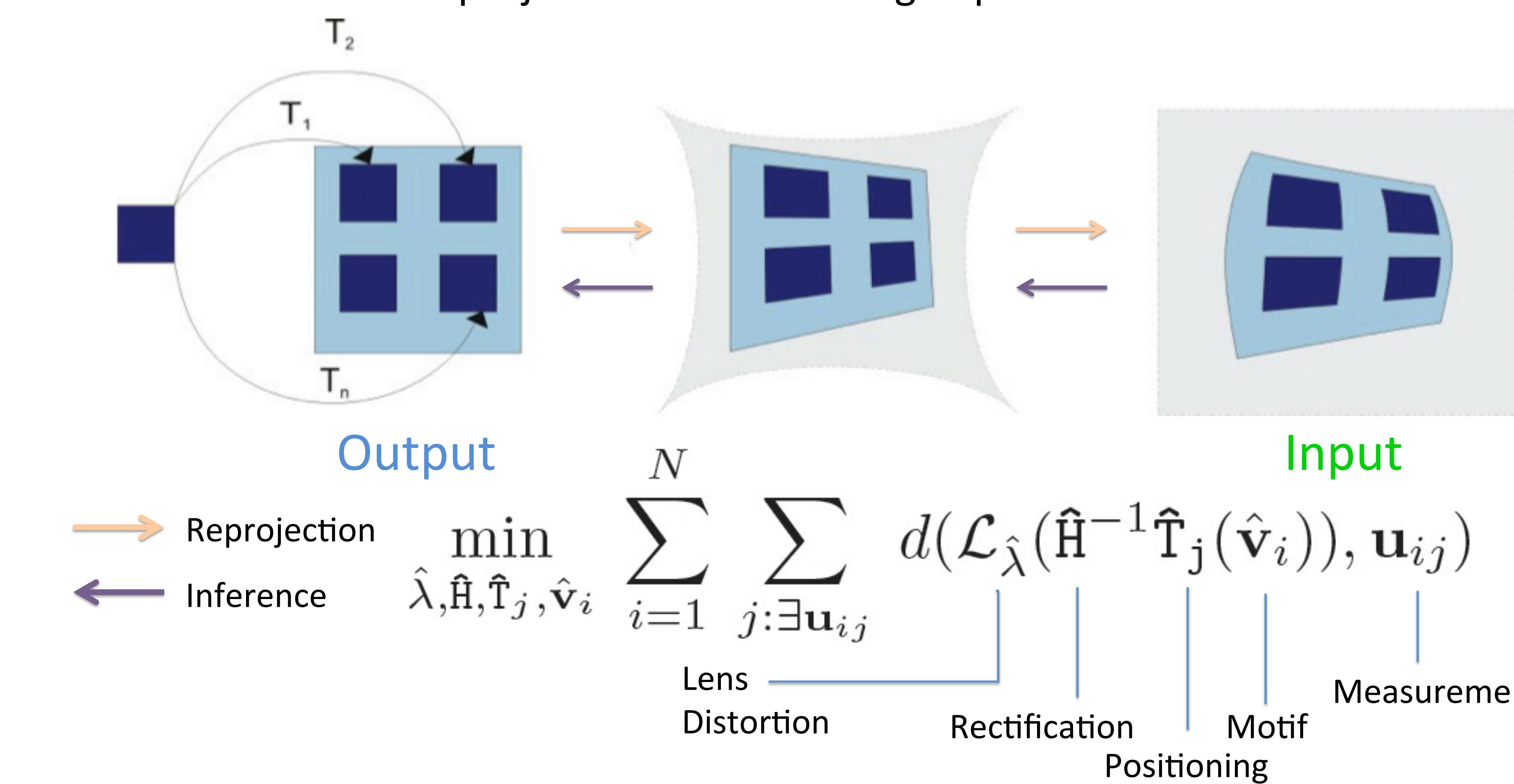


Configuration II: Two rotated features

Result: Metric Rectification

**Generative Model**

- Repeated pattern is explicitly modeled in rectified space
- Lens distortion estimated as a nuisance parameter
- Input to inference algorithm is ONLY an *unannotated image*
- Distance from reprojected model to imaged pattern minimized

**Pattern Estimation**

- Estimate rectification and pattern jointly from an image
- 1. SIFTs extracted from image and clustered
- 2. Rectification estimated from linear constraints
- 3. Clusters verified against scale constraint to make repeats
- 4. Geometric hashing of LAFs in rectified space to construct motifs
- Refine pattern, rectification and model lens distortion by minimizing reprojection error of model

Rectifications With Segmentations